



PATENT

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

Michael Weber-Grabau, et al.

Application No.: 09/927,102

Filed: August 10, 2001

For: CRITICAL DIMENSION
METROLOGY SYSTEM
INTEGRATED INTO
SEMICONDUCTOR WAFER
PROCESS TOOL

Group Art Unit: 2877

Examiner: Richard A. Rosenberger

**RESPONSE TO OFFICE ACTION
MAILED OCTOBER 3, 2003**

121 Spear Street, Suite 290
San Francisco, CA 94105
(415) 512-1312

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited
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Box 1450, Alexandria, VA 22313-1450 on Dec. 15, 2003.

STALLMAN & POLLOCK LLP

Dated: 12/15/2003

By: Georgia K. Smith

Georgia K. Smith

Sir:

In response to the Office Action mailed October 3, 2003, please amend the above-identified application as follows:

Amendment to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 10 of this paper.

12/18/2003 CNGUYEN 00000029 09927102

01 FC:2202
02 FC:2201

18.00 OP
86.00 OP

Atty Docket No.: TWI-31000